FINAL PPT

WAFER SCALE DATA PROCESSING

PROGRAMMING FOR ENGINEERS 2

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Wafer scale data processing

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Question & Answer

#1 Project Background

WAFER SCALE DATA PROCESSING



WAFER-SCALE DATA ANALYSIS

Work to improve product quality by preventing and analyzing defects that occur on wafers using various measurement equipment and sensors



MACH-ZENDER MODULATOR

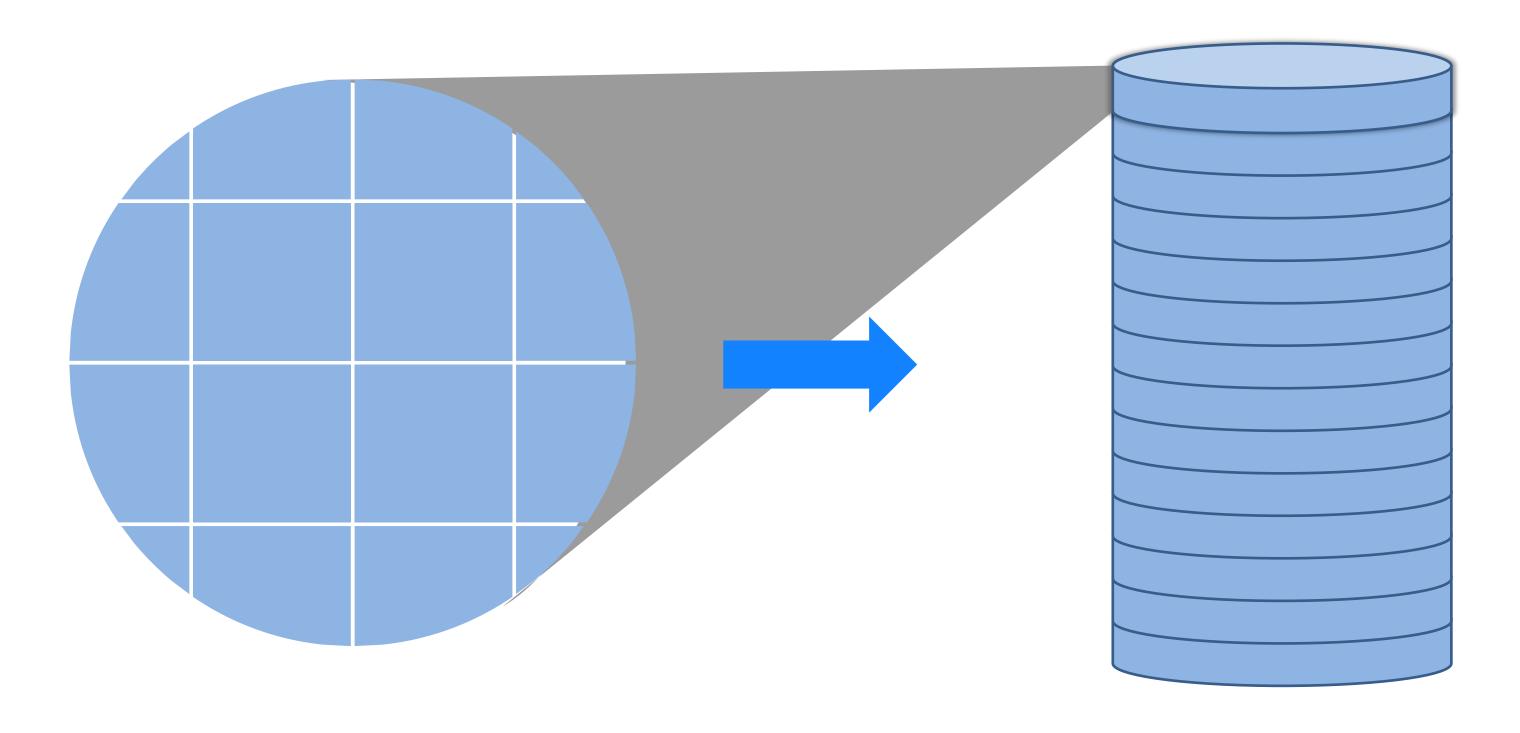
The Mach-Zehnder modulator divides light into two branches and creates various data through modulation and interference, while also converting light into electrical signals.



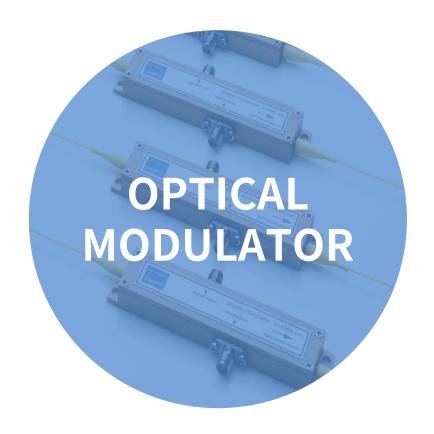
AUTOMATION PROCESS

Streamline your operations and increase efficiency with our cutting-edge automation process, empowering you to achieve higher productivity and superior quality while minimizing manual intervention

소자의 크기가 작아질수록 웨이퍼 당 **데이터 급증**!



"DATA ANALYSIS IS ABOUT TELLING A STORY, NOT JUST OBTAINING INFORMATION" – JOHN TUKEY



Mach-Zender MODULATOR

Converting light signals into electrical signals



XML DATA

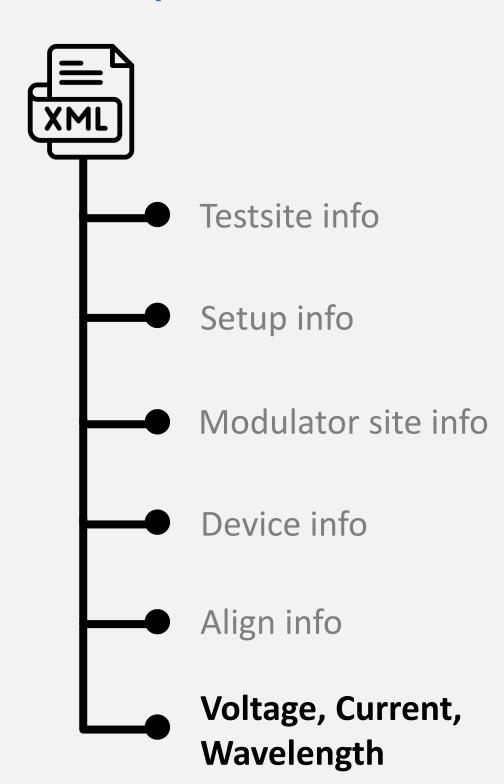
Stored data have an amount of hierarchical structure



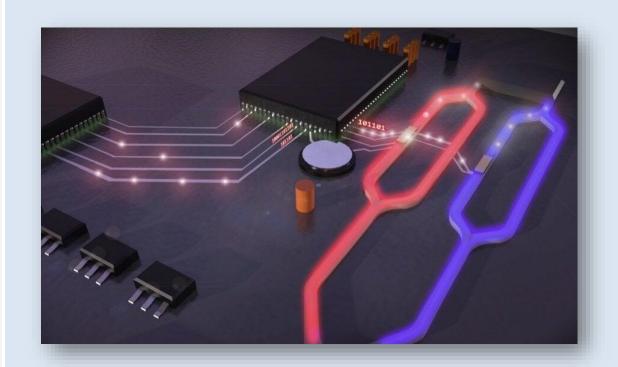
CSV/PNG FILES

analyze graphs and data files with extracted values

- Data input



- Modeling

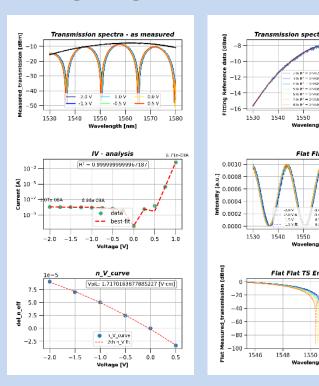


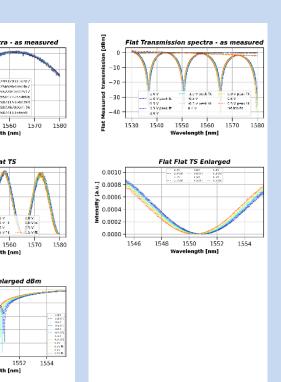


- ✓ IV curve
- ✓ Transmission spectra
- ✓ nV curve & VpiL

- Visualization & Output

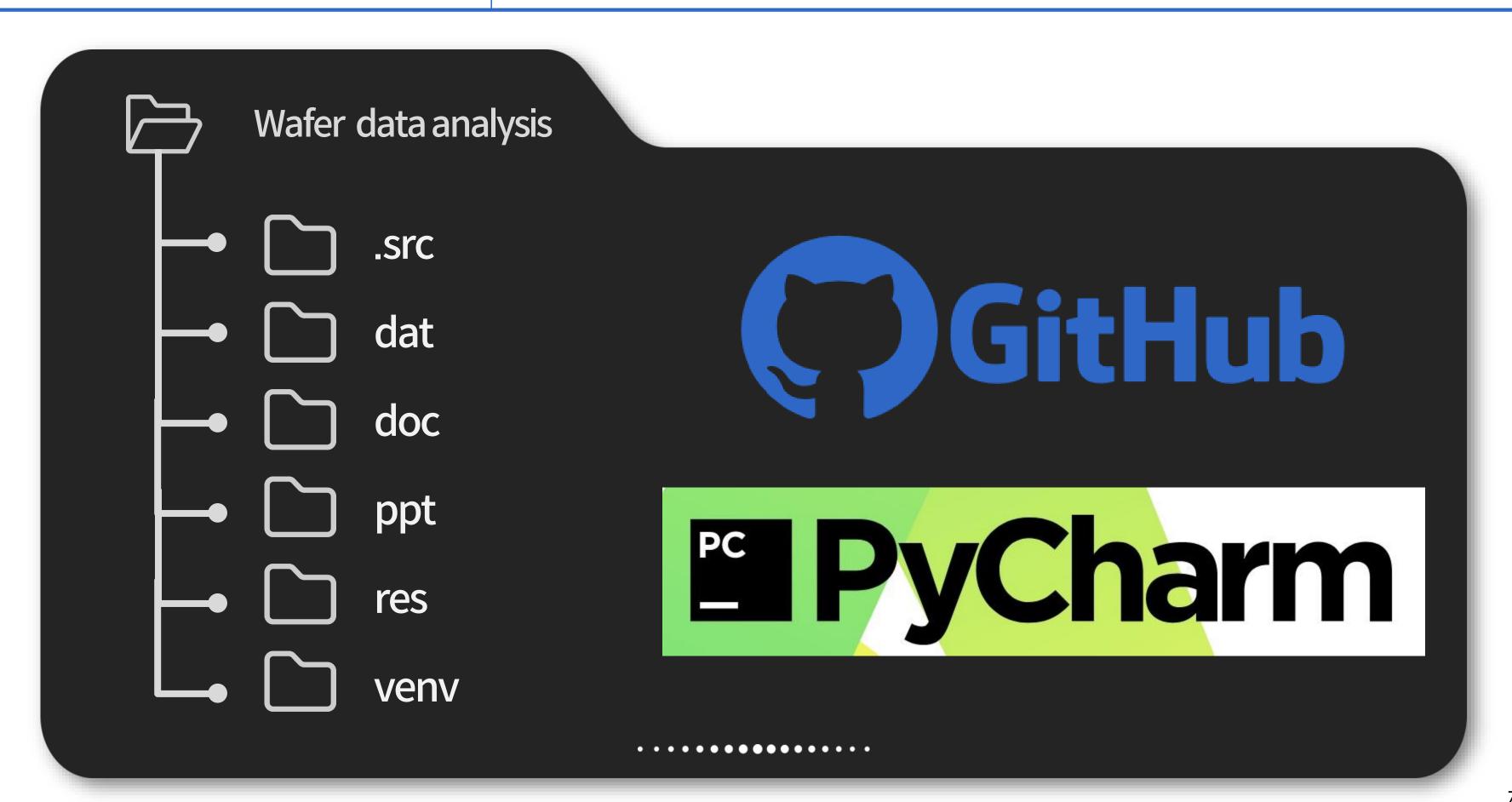
PNG file





CSV file

	Α	В	С	D	E	F	G	н	1	J	K	L	М	N	0	Р	Q	R	S	Т	U	V	W
1	Lot	Wafer	Mask	TestSite	Name	Date	Script ID	Script Ve	Script Ov	Operator	Row	Column	ErrorFlag	Error des	Analysis \	Rsq of Re	Max trans	Rsq of IV	l at -1V [/	l at 1V [A	n_eff_0V	VpiL	
2	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process l	0.1	D_노정완	ykim	-1	-1	0	No Error	1550	0.99843	-7.8517	1	2.60E-08	0.0067	4.18735	1.63449	
3	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process l	0.1	D_노정완	ykim	-1	-3	0	No Error	1550	0.99723	-9.0545	1	4.89E-08	0.00633	4.21082	1.57324	
4	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	-1	3	0	No Error	1550	0.99717	-9.4873	1	4.59E-08	0.00638	4.20868	1.47744	
5	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process l	0.1	D_노정완	ykim	-3	-3	0	No Error	1550	0.99616	-8.3437	1	5.47E-08	0.00632	4.18164	1.61091	
6	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	-3	0	0	No Error	1550	0.9981	-8.9119	1	4.81E-08	0.00653	4.20911	1.50887	
7	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process l	0.1	D_노정완	ykim	-3	2	0	No Error	1550	0.99888	-9.5159	1	6.66E-08	0.00652	3.34948	-0.1081	
8	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	-4	-1	0	No Error	1550	0.9951	-9.5593	1	7.78E-08	0.0064	4.18105	1.44582	
9	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	0	-4	0	No Error	1550	0.99719	-9.7245	1	6.76E-08	0.00604	4.19143	1.51507	
10	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	0	0	0	No Error	1550	0.99859	-7.7879	1	8.96E-09	0.00671	4.18644	1.71702	
11	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	0	2	0	No Error	1550	0.99738	-8.0119	1	4.15E-08	0.00659	4.18148	1.50803	
12	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	2	-1	0	No Error	1550	0.9983	-8.1817	1	4.59E-08	0.00638	4.18109	0.66278	
13	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	2	-3	0	No Error	1550	0.99821	-9.454	1	6.18E-08	0.00607	4.20703	1.49147	
14	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	2	2	0	No Error	1550	0.99678	-8.3448	1	4.80E-08	0.00613	4.19054	1.6386	
15	HY20210	D07	LION1	DCM_LM2	MZMCTE	2019071	5 process L	0.1	D_노정완	ykim	3	0	0	No Error	1550	0.99895	-8.7763	1	4.97E-08	0.00595	4.2168	1.56595	



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PROGRAMMING FOR ENGINEERS 2



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